AMENDMENTS TO THE CLAIMS

Please amend the claims as follows:

1. (Currently Amended) A charged particle beam device, comprising:

an emitter array for emitting a plurality of charged particle beams;

an extraction member for extracting the plurality of charged particle beams;

[[one]] a lens for imaging the plurality of charged particle beams;

[[one]] an electrode unit for accelerating the plurality of charged particle beams; and

a first control unit and a second control unit for controlling potential differences between a first potential of the emitter array, a second potential of the electrode unit, and a third potential of a specimen, wherein the second potential is capable of accelerating the plurality of charged particle beams with respect to the first potential and the third potential is capable of decelerating the plurality of charged particle beams with respect to the second potential.

2. (Previously Presented) The charged particle beam device of claim 1, wherein the third potential is capable of defining a charged particle beam energy on impingement of the plurality of charged particle beams on the specimen such that it corresponds to a potential of maximal 5 kV; and

the second potential is capable of increasing the charged particle beam energy to an energy that is at least a factor of 5 higher than the energy corresponding to the third potential.

3. (Canceled)

4. (Previously Presented) The charged particle beam device of claim 1, further comprising;

an emitting angle defining member for controlling the emitting angle of the plurality of charged particle beams.

5. (Previously Presented) The charged particle beam device of claim 1, wherein the emitter array is spaced from a specimen stage by at least 10 mm.

6. (Previously Presented) The charged particle beam device of claim 1, further comprising a further electrode unit biased to a potential which is capable of increasing the charged particle beam energy with respect to the energy corresponding to the third potential by at least a factor of 5.

7. (Previously Presented) The charged particle beam device of claim 1, wherein the lens for imaging the plurality of charged particle beams comprises a unit for providing a homogenous magnetic field, wherein the unit for providing the homogenous magnetic field comprises at least one coil.

8. (Previously Presented) The charged particle beam device of claim 7, wherein the unit for providing a homogenous magnetic field further comprises at least a second coil.

9. (Previously Presented) The charged particle beam device of claim 7, wherein the unit for providing a homogenous magnetic field further comprises at least one pole piece.

10. (Previously Presented) The charged particle beam device of claim 1, further comprising a deflection system for deflecting the plurality of charged particle beams.

11. (Previously Presented) The charged particle beam device of claim 10, wherein the deflection system for deflecting the plurality of charged particle beams comprises a magnetic deflector for deflecting the plurality of charged particle beams.

12. (Previously Presented) The charged particle beam device of claim 10, wherein the deflection system for deflecting the plurality of charged particle beams comprises a plurality of electrostatic deflectors for individually deflecting the charged particle beams.

13. (Previously Presented) The charged particle beam device of claim 10, wherein the deflection system for deflecting the plurality of charged particle beams comprises an electrostatic deflector for deflecting the plurality of charged particle beams.

14. (Previously Presented) The charged particle beam device of claim 6, wherein the electrode unit, the further electrode unit, or both are capable of providing a vacuum isolation.

15. (Previously Presented) The charged particle beam device of claim 14, wherein the vacuum isolation is provided by a transparency ratio between the area of apertures and the area of solid material of smaller than 1:100.

16. (Previously Presented) The charged particle beam device of claim 1, wherein the third potential is capable of defining the charged particle beam energy on impingement of the plurality of charged particle beams on the specimen such that it corresponds to a potential of maximal 1 kV.

17. (Previously Presented) The charged particle beam device of claim 1, wherein the second potential is capable of increasing the charged particle beam energy to an energy that is at least a factor of 10 higher than the energy corresponding to the third potential.

18. (Previously Presented) The charged particle beam device of claim 9, wherein the unit for providing a homogenous magnetic field further comprises a lower pole piece which is movable with respect to the at least one pole piece.

19. (Previously Presented) The charged particle beam device of claim 1, wherein the charged particle device is a minicolumn.

20. (Currently Amended) A method of imaging a plurality of charged particle beams, comprising:

emitting the plurality of charged particle beams with an emitter array system;

focusing the plurality of charged particle beams on a specimen with one lens;

providing a first potential to the emitter array;

providing a second potential to an extraction member so that the plurality of particle beams are extracted;

providing a ~~second~~ third potential to one electrode unit such that the plurality of charged particle beams are accelerated; and

providing a ~~third~~ fourth potential to a specimen such that the plurality of charged particle beams are decelerated before impingement on the specimen.

21. (Currently Amended) The method of claim 20, wherein the ~~third~~ fourth potential is provided such that the plurality of charged particle beams impinge on the specimen with an energy corresponding to maximal 5 kV; and

the ~~second~~ third potential is provided such that the plurality of charged particle beams are accelerated to an energy at least 5 times higher than the energy on impingement on the specimen.

22. (Previously Presented) The method of claim 20, further comprising:

providing a first vacuum in a first region between the emitter array and the electrode unit;

providing a second vacuum in a second region between the electrode unit and the specimen; and

wherein the pressure in the first vacuum is at least a factor of 10 lower than the pressure in the second vacuum.

23. (Previously Presented) The method of claim 20, further comprising:

deflecting the plurality of charged particle beams.